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- Apel, O.; Mann, K.; Heber, J.; Thielsch, R.: Nonlinear absorption phenomena in oxide coatings for 193 nm In: Gregory J. Exarhos; Arthur H. Guenther; Mark R. Kozlowski; Keith L. Lewis; M. J. Soileau (eds.): Laser-Induced Damage in Optical Materials, Proc. SPIE vol. 3902, p. 235-241; Bellingham: SPIE, 2000; ISBN 0-8194-3508-2
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Lectures and Poster Sessions

Bernitzki, H.; Duparré, A.; Giech, S.; et al.: Reflectance and scatter losses of 157 nm HR-coatings
Poster: SEMATECH International Symposium on 157 nm, 14-16 November 2000, San Diego, CA, USA

Bräuer, A.; Gabler, T.; Elflein, W.; Hörhold, H.-H.: Nonresonant c(3)-nonlinearities in polyconjugated PPV-polymers investigated by waveguide methods
Lecture: COST Meeting, June 2000, Patras, Greece

Bräuer, A.; Kießling, H.; Dannberg, P.: Replication of refractive and diffractive optical elements
Lecture: EUSPEN-Seminar on Precision Engineering and Microtechnology, 19-20 July 2000, Aachen, Germany

Bräuer, A.: Neuartige mikrooptische Module basierend auf UV-gestützten Herstellungstechnologien in Polymeren
Lecture: Institutsseminar des Max-Born-Instituts, October 2000, Berlin, Germany

Bräuer, A.; Dannberg, P.; Mann, G.: Präzisionsmikrooptik in temperaturstabilen Polymeren
Lecture: Workshop Mikrooptik, October 2000, Hagen, Germany

Brenner, K.-H.; Bähr, J.; Schmelcher, T.; Zeitner, U.D.: Design and fabrication of arbitrary non-separable continuous phase elements
Lecture: Topical meeting, 18–22 June 2000, Quebec, Canada

Duparré, A.: Metrologie in Mikro- und Nanotechnik
Lecture: Wissenschaftliche Tage der Westsächsischen Hochschule Zwickau, 26 October 2000, Zwickau, Germany

Duparré, A.: Scatter measurement with 157 nm techniques
Lecture: Third International UV Laser Symposium for 157 nm, 1-2 November 2000, Fort Lauderdale, USA

Duparré, A.; Kozhevnikov, I.; Giech, S.; Steinert, J.; Notni, G.: Surface characterization of optical components for the DUV, VUV, and EUV
Lecture: MNE - International Conference on Micro- and Nanoengineering 2000, 18-21 September 2000, Jena, Germany

Duparré, A.; Notni, G.: Methoden zur Charakterisierung von Oberflächen und Schichten
Lecture: Fachseminar begleitend zur 5. Optatec- International Trade Fair for Optics and Optoelectronics, June 2000, Frankfurt: Diffractive Optics and Micro Optics 2000, 18-22 June 2000, Quebec, Canada

Dannberg, P.; Bräuer, A.; Göring, R.: Replication for precise microoptical structures
Poster: Conference on Micro- and Nano-Engineering, September 2000, Jena, Germany

Eberhardt, R.: State of the art and future requirements for optical transparent adhesives in microoptics and optoelectronics
Lecture: IEEE-CPMT Workshop Poly 2000; 4-5 December 2000, London, UK

Feigl, T.; Yulin, S.; Kaiser, N.: EUV-multilayers with high thermal stability
Poster: 5th International Conference on the Physics of X-Ray Multilayer Structures, 5-9 March 2000, Chamonix, France

Feigl, T.; Lauth, H.; Yulin, S.; Kaiser, N.: Heat resistance of EUV multilayer mirrors for long-time applications
Lecture: MNE - International Conference on Micro- and Nanoengineering 2000, 18-21 September 2000, Jena, Germany

Ferrari, M.; Tenner, I.; Figulla, H.R.; Damm, C.; Peschel, T. Weber, C.: Percutaneous transvascular aortic valve replacement with self-expanding stent valve device
Lecture: Konferenz SMIT 2000, 6-9 September 2000, Gelsenkirchen, Germany

Gatto, A.: IOF UV mirrors and SR Irradiation
Lecture: Optics workshop "Storage Ring Free Electron Laser at 200 nm", Institut Fresnel - LOSCM, Marseille, 07 July 2000, Marseille, France

Gatto, A.: UV-R-and T mappings for FEL irradiated mirrors
Lecture: Optics workshop "Storage Ring Free Electron Laser at 200 nm", Institut Fresnel - LOSCM, Marseille, 07 July 2000, Marseille, France

Gatto, A.: Materials structural properties investigations on EBD and PIAD irradiated UV mirrors
Lecture: Optics workshop "Storage Ring Free Electron Laser at 200 nm", Institut Fresnel - LOSCM, Marseille, 07 July 2000, Marseille, France

Gatto, A.: Hard UV Optics for Hostile Environment - Materials - Design - Irradiation Tests
Lecture: School of Optics - CREOL, University of Central Florida, 23 October 2000, Orlando, USA

Gatto, A.; Kaiser, N.: Hard mirrors for Free Electron Laser Lecture: Lawrence Livermore National Laboratory (LLNL), University of California, 28 July 2000, Livermore, CA, USA	Kaiser, N.: Neue Anwendungsfelder optischer Schichten Lecture: Fachseminar begleitend zur 5. Optatec- International Trade Fair for Optics and Optoelectronics, June 2000, Frankfurt, Germany	Karthe, W.: Montage mikrooptischer Systeme Lecture: Workshop Optische Techno- logien für das 21. Jahrhundert, 13-15 February 2000, Stuttgart, Germany
Gatto, A.; Kaiser, N.: Resistant UV mirrors for Free Electron Lasers, Manufacture – charcterizations – degradation tests Lecture: X. International Conference Nonresonant Laser-Matter interaction – NLMI-10, 21-23 August 2000, St. Petersburg, Russia	Kaiser, N.: Advances in optical interference coatings Lecture: OPTO 2000 – 4 th International Conference and Exhibition on Optoelectronics, May 2000, Erfurt, Germany	Kießling, H.: Replikation feinststrukturierter optischer Oberflächen für diffraktive und integriert optische Elemente Lecture: Workshop Optische Technologien für das 21. Jahrhundert, 13-15 February 2000, Stuttgart, Germany
Gatto, A.; Kaiser, N.; et al.: Achromatic damage investigations on mirrors for UV-free electron lasers Lecture: XXXII Annual Symposium on Optical Materials for High Power Lasers, 16-18 October 2000, Boulder, CO, USA	Kaiser, N.: Vakuumgestützte Zukunftstechno- logien in der Optik Lecture: Frühjahrstagung der Deutschen Physikalischen Gesell- schaft, 27-31 March 2000, Regensburg, Germany	Kuhlmann, T.: Beschichtungen für kurze und extrem kurze Wellenlängen Lecture: Fachseminar begleitend zur 5. Optatec- International Trade Fair for Optics and Optoelectronics, June 2000, Frankfurt, Germany
Gatto, A.; Thielsch, R.: Realization of a double band mirror at 220 nm and 380 nm Lecture: Optics workshop "Storage Ring Free Electron Laser at 200 nm", Eindhoven University, Eindhoven, 23 November 1999, The Netherlands	Kalkowski, G., Risse, S., Harnisch, G., Guyenot, V.: Electrostatic chucks for lithography applications Poster: MNE - International Conference on Micro- and Nanoengineering 2000, 18-21 September 2000, Jena, Germany	Kuhlmann, T.; Feigl, T.; Yulin, S.; Kaiser, N.: Damage resistant Si-based multilayer mirrors Poster: 2 nd International Workshop on EUV-Lithography, 17-19 October 2000, San Francisco, USA
Gliech, S.; Duparré, A.; Notni, G.: Streulichtmessanordnung zur Unter- suchung von Oberflächen und Schich- ten für die Optik, Halbleitertechnik, Kunststoff- und Materialverarbeitung Poster: 101. Jahrestagung der DGaO, 13-17 June 2000, Jena, Germany	Karthe, W.: Microoptical Components and Systems Lecture: MICROtec 2000, 25-27 September 2000, Hannover, Germany	Kühmstedt, P.; Heinze, M.; Schreiber, W.: Korrektur von 3-D Messdaten durch Konsistenzprüfung Poster: 101. Jahrestagung der DGaO, 13-17 June 2000, Jena, Germany
Guyenot, V.; Eberhardt, R.: Montage und Justierung mikrooptischer Bauelemente Lecture: Innovationskolloquium Universität Klagenfurt, 28 September 2000, Klagenfurt, Germany	Karthe, W.: Herstellung mikrooptischer Kompo- nenten und Systeme Lecture: Mikrotechnische Produktion – quo vadis? Forschungszentrum Karls- ruhe, 29 November 2000, Karlsruhe, Germany	Laux, S.; Bernitzki, H.; Klaus, M.; Lauth, H.; Kaiser, N.: Long time radiation resistant optical coatings for UV-Excimer laser applications Lecture: XXXII Annual Symposium on Optical Materials for High Power Lasers, 16-18 October 2000, Boulder, CO, USA

Laux, S.; Bernitzki, H.; Lauth, H.; Kaiser, N.: Optische Schichten für die 248 nm-Excimerlaseranwendung Lecture: 101. Jahrestagung der DGaO, 13-17 June 2000, Jena, Germany	Notni, G.: Selbstkalibrierendes 3D-Messsystem "kolibri" Lecture: 5. IPA-Anwenderforum Rapid Product Development, 5-6 September 2000, Stuttgart, Germany	Pertsch, T.; Glas, P.; Wrangle, M.; Lederer, F.: An all fiber phase locking setup for multicore fiber lasers Lecture: 2000 Conference on Lasers and Electro-Optics Europe, 10-15 September 2000, Nice, France
Letzkus, F.; Butschke, J.; Eberhardt, R.; Mohaupt, M.; et al.: Manufacturing process of a measuring device for the pattern lock system in the ion beam lithography Poster: MNE - International Conference on Micro- and Nanoengineering 2000, 18-21 September 2000, Jena, Germany	Notni, G.: 3-D Vermessung: Bedeutung für die Zahnheilkunde Lecture: Bundesfachschaftstagung Zahnmedizin – BuFaTa 2000, 2-4 June 2000, Jena, Germany	Pertsch, T.; Glas, P.; Wrangle, M.; Lederer, F.: An all fiber phase locking setup for multicore fiber lasers Poster: 2000 Conference on Lasers and Electro-Optics Europe, 10-15 September 2000, Nice, France
Luthardt, R.; Kühmstedt, P.; Faust, A.: Girrbach-Dentaltechnik GmbH – CAD/CAM-Systeme in der Zahnmedizin Lecture: Informationsveranstaltung für Zahnärzte, 5 April 2000, Baunatal, Germany	Notni, G.; Duparré, A.: Oberflächencharakterisierung und Sub-Surface- Defekterkennung an optischen Funktionsflächen Lecture: Optik-Kolloquium 2000, Institut für Technische Optik, 23 February 2000, Stuttgart, Germany	Pertsch, T.; Peschel, U.; Lederer, F.: Wannier-Stark solitons in waveguide arrays with linear potential Lecture: NATO Advanced Research Workshop "Nonlinearity and Disorder: Theory and Applications"; 2-6 October 2000, Tashkent, Uzbekistan
Luthardt, R.; Holzhüter, M.; Kühmstedt, P.; Walter, M.: Digital 3D-measurements of the dimensional stability of gypsum master casts Poster: International Association of Dental Research, Central European Division, 24-26 August 2000, Warsaw, Poland	Notni, G.; Reichel, F.: Design and application of LC, DMD, and laser projection systems for 3D-shape measurement Lecture: 12 th International Symposium on Electronic Imaging, January 2000, San Jose, USA	Peschel, T.; Damm, C.; Gebhardt, A.; Kirschstein, U.C.: Adjustment and mounting of stencil masks for Ion Projection Lithography Lecture: MNE - International Conference on Micro- and Nanoengineering 2000, 18-21 September 2000, Jena, Germany
Mohaupt, M.; Eberhardt, R.; Bär, M.; Kölbel: Vereinzen und Ordnen von Mikrobauteilen aus dem Schüttgut Lecture: 2. Öffentliches Statusseminar µfeed 2, 18 October 2000, Villingen-Schwenningen, Germany	Notni, G.H.; Notni, G.: Simultanes Erfassen der 3D-Form und Farbe mittels Streifenprojektion bei Beobachtung mit Monochromkameras Poster: 101. Jahrestagung der DGaO, 13-17 June 2000, Jena, Germany	Peschel, T.; Damm, C.; Risse, S.; Kirschstein, U.C.: Wafer stage assembly for Ion Projection Lithography Lecture: MNE - International Conference on Micro- and Nanoengineering 2000, 18-21 September 2000, Jena, Germany
Mohaupt, M.; Steinkopf, R.; Eberhardt, R., Bär, M.: Handhabungssystem zur Prüfung mikromechanischer Komponenten Lecture: 2. Öffentliches Statusseminar µfeed 2, 18 October 2000, Villingen-Schwenningen, Germany	Pertsch, T.; Dannberg, P.; Elflein W.; Bräuer, A.; Peschel, U.; Lederer, F.: Temperature controlled beam steering in polymer waveguide arrays Lecture: International Symposium on Optical Science and Technology, 30 July - 4 August 2000, San Diego, CA, USA	

Pfeil v.; Wyrowski, F.: Strukturdesign optischer Elemente unter Anwendung der Näherung lokaler ebener Grenzflächen Lecture: 101. Jahrestagung der DGaO, 13-17 Juni 2000, Jena, Germany	Schulz, U.: Beschichtung von Kunststoffen für die Optik Lecture: Fachseminar begleitend zur 5. Optatec- International Trade Fair for Optics and Optoelectronics, June 2000, Frankfurt, Germany	Uhendorf, K.; Notni, G. Kowarschik, R.: Auflösungserhöhung durch die Ausnutzung von Interferenzeffekten in konfokalen Mikroskopen mit phasenkonjugierendem Spiegel Lecture: 101. Jahrestagung der DGaO, 13-17 June 2000, Jena, Germany
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